

Modeling of metallic interfaces under high electric fields for particle accelerators

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Acknowledgements:

Soumendu Bagchi, Ryo Shinohara, Gaoxue Wang, Sergey Barishev, Evgenya Simakov
LANL LDRD program



Ryo
Shinohara

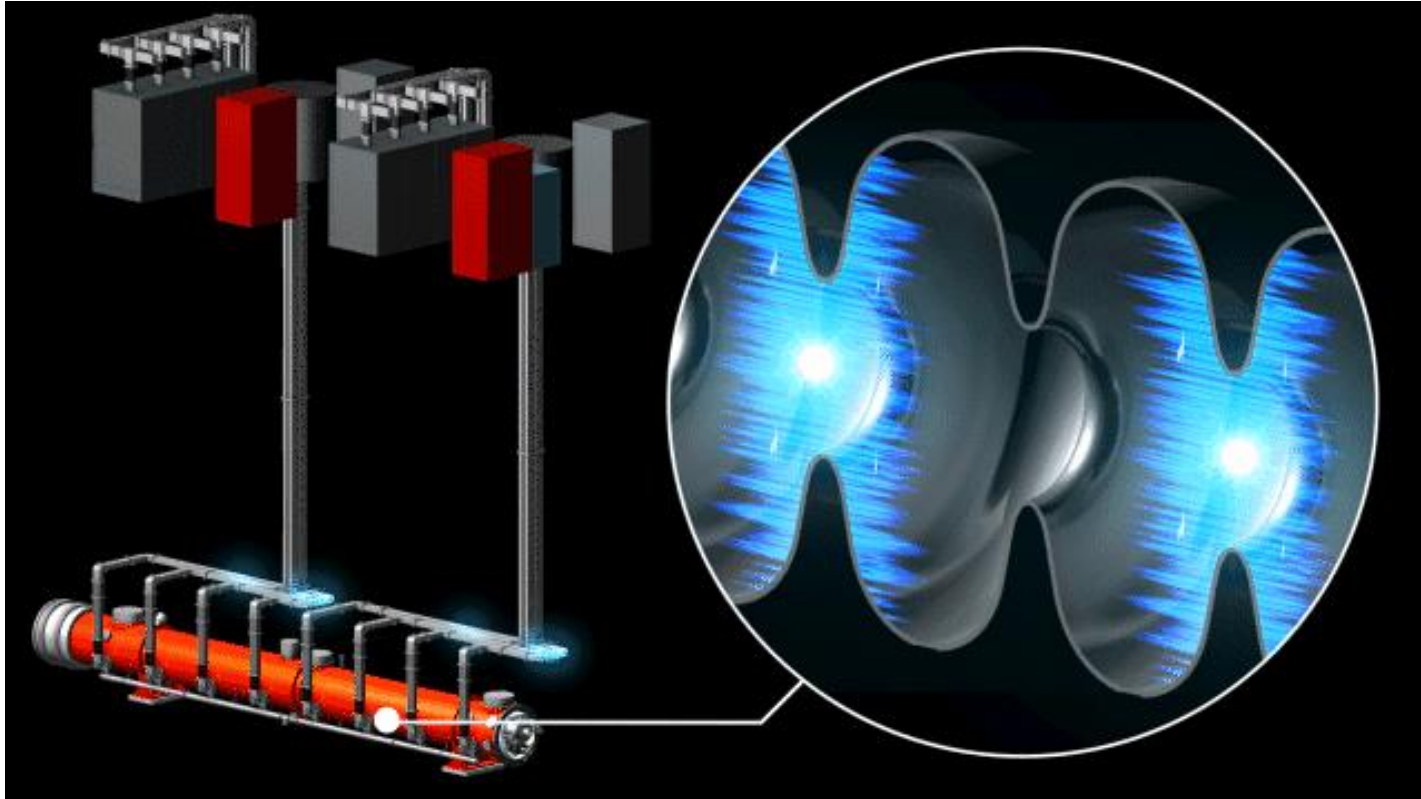


Soumendu
Bagchi



Gaoxue
Wang

Particle accelerators 101



Greg Stewart/SLAC National Accelerator Laboratory

Basic parameters

- **Average accelerating gradient – 100-200 MV/m**
- **Peak surface electric field – 200-400 MV/m**
- RF frequency – 10 GHz
- Pulse length – 100 ns
- Repetition rate – 100 Hz
- Input power – 50 MW
- Pulse energy – 10 J
- Cavity is usually made of Cu

The race to higher fields

Increasing accelerating fields is generally beneficial:

- Smaller size (medical, space applications)
- Lower cost (material, footprint)
- Higher energies

Limiting factors:

- Available RF power
- Multipacting: resonant electron–avalanche
- Losses: ohmic heating and thermal fatigue
- Vacuum breakdown



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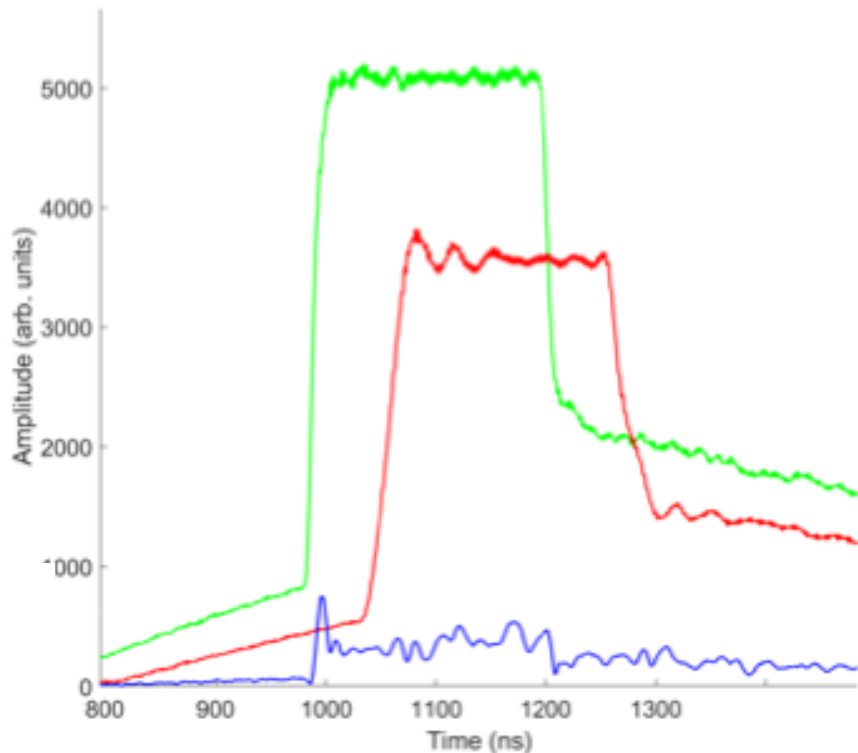
Breakdown for accelerator operators

Incident power

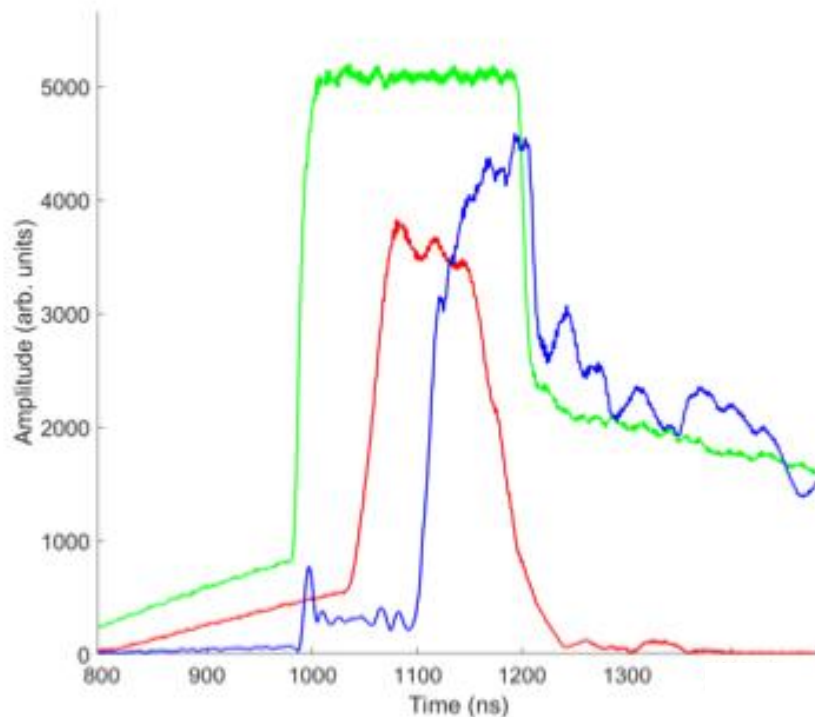
Transmitted power

Reflected power

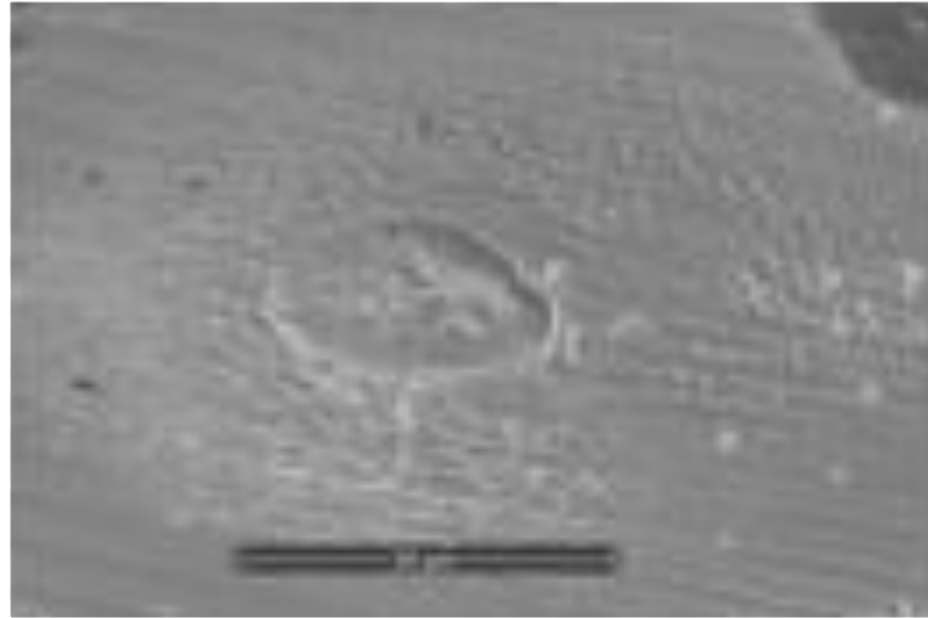
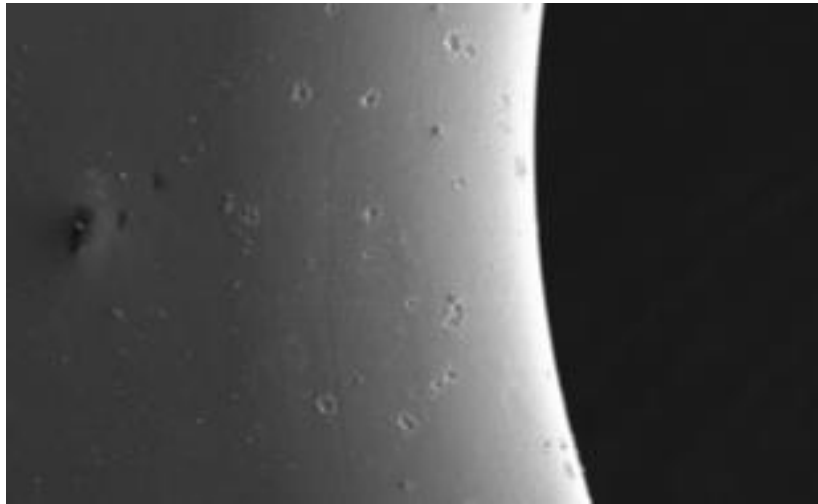
Normal



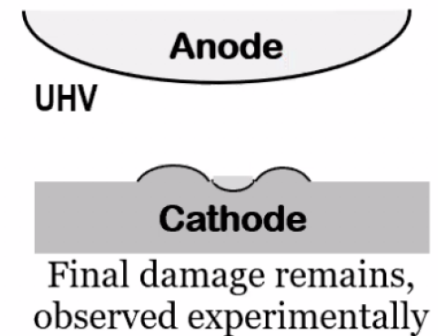
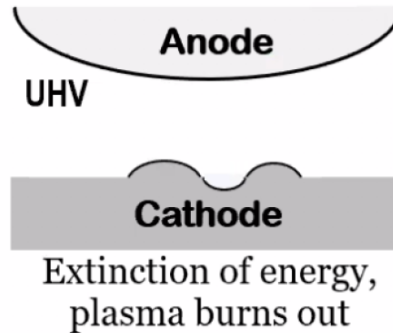
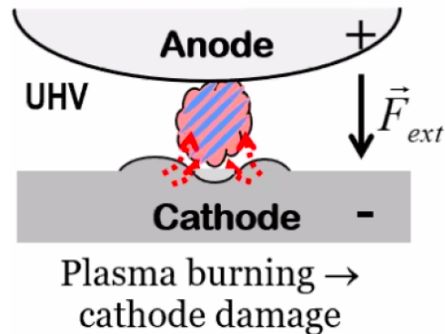
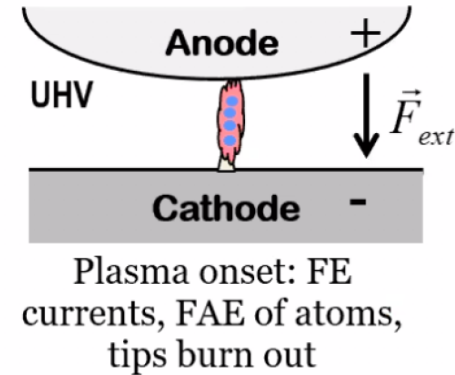
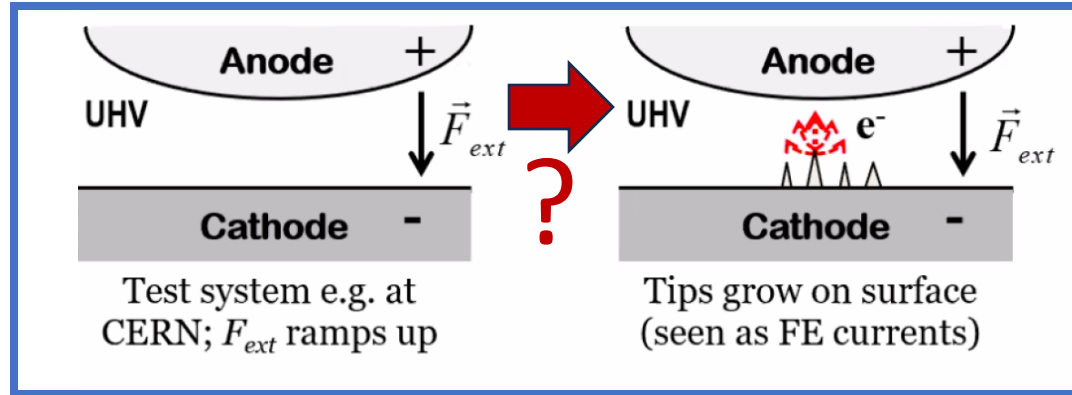
Breakdown



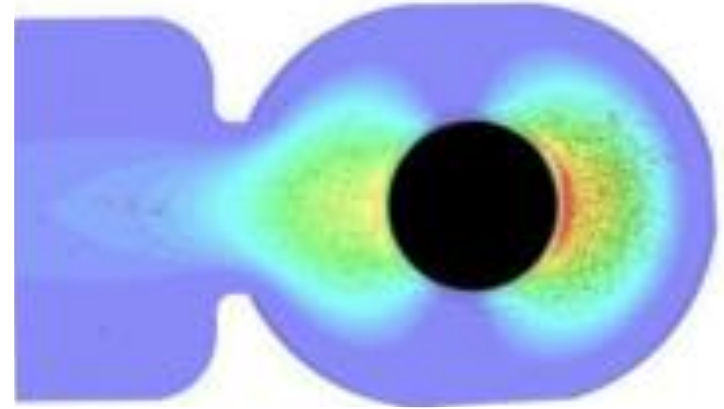
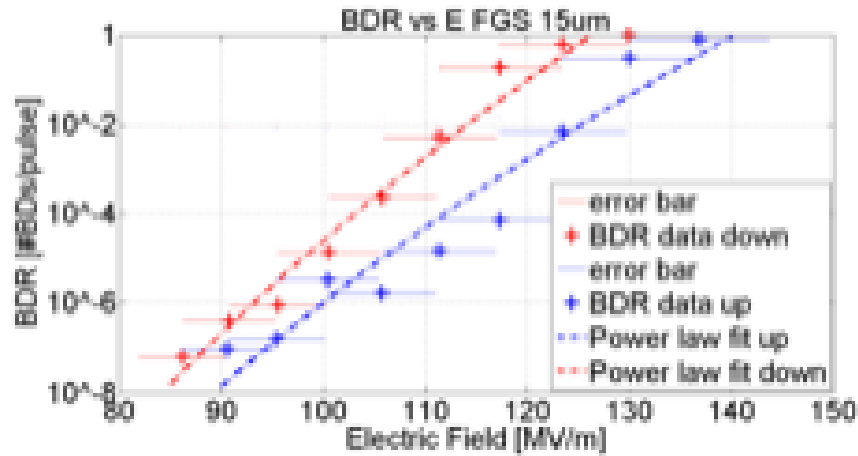
Breakdown for materials scientists



Breakdown: what do (we think) we know?

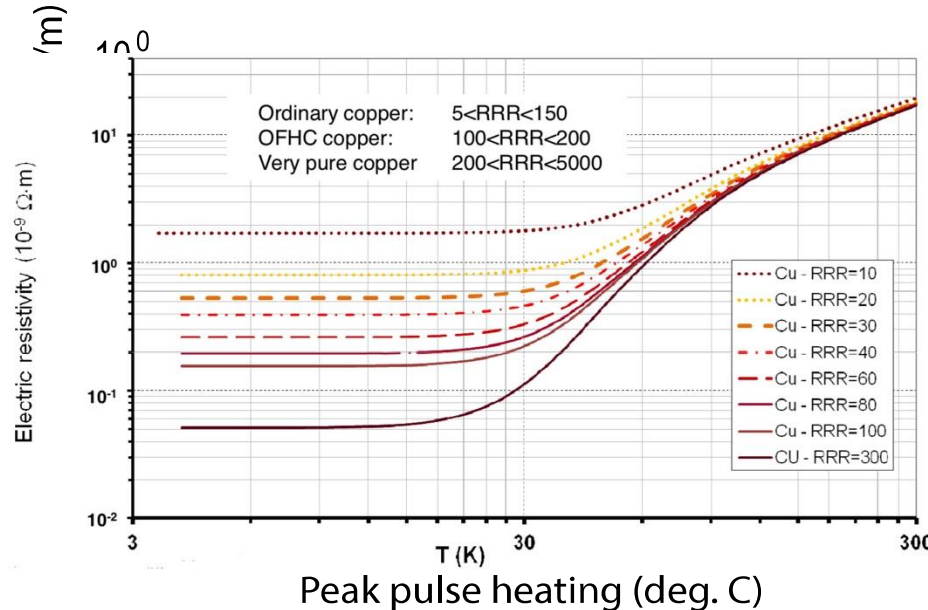


Possible driving force: Electric field



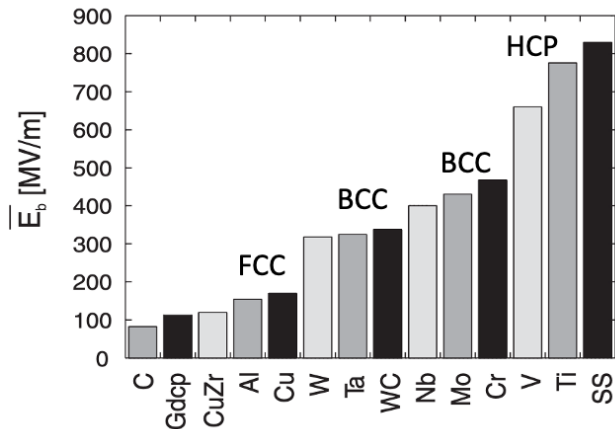
- Concentrates in high E-field regions (but not exclusively)
- Extremely steep field dependence (E^{20-40})!

Possible driving force: RF Losses



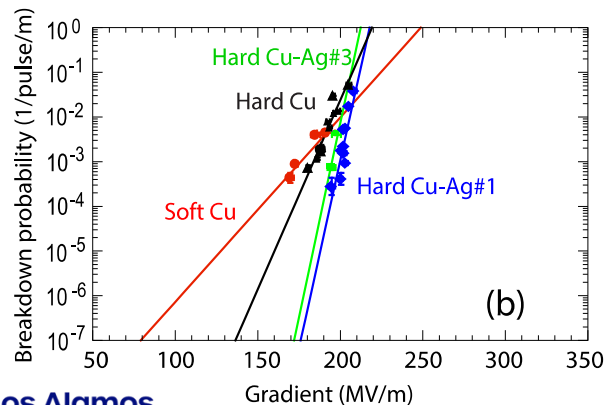
- RF pulses cause cyclic Joule heating near the surface (skin depth $\sim \mu m$)
- BDR scales with peak pulse heating
- Losses and BDR significantly decrease in cryogenic conditions

Vignette #1: Plastic-deformation induced roughening



Material properties matter:

- Harder materials = lower BDR
- Processing matters (welding, ...)

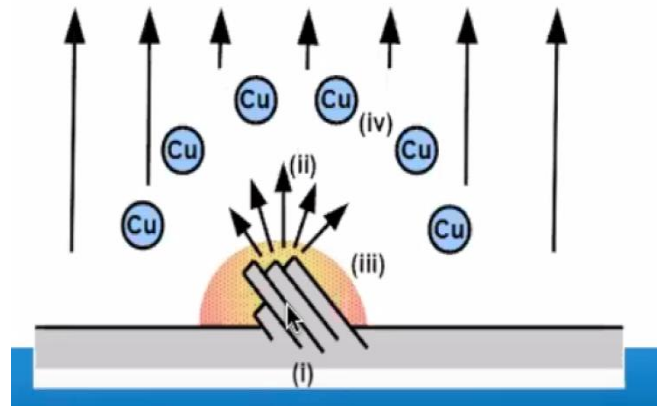


- Possible relevant physics:

- **Plastic deformation**
- **Dislocation motion/multiplication**
- Microstructure
- Fatigue
- ...

Vignette #1: Plastic-deformation induced roughening

- Runaway dislocation multiplication has been hypothesized as a breakdown precursor
- Current analytical models have yet to be demonstrated in simulations
- Goal: **assess dislocation-multiplication processes using molecular dynamics**



MD of metals under E field

- Conventional charge-equilibration (QEq):

$$\min_{\mathbf{q}} \quad E_{\text{elec}}(\mathbf{q}) = \sum_i^N \chi_i q_i + \frac{1}{2} \sum_{i,j}^N H_{ij} q_i q_j$$

$$\text{subject to } \sum_i^N q_i = 0$$

$$H_{ij} = \delta_{ij} \eta_i + (1 - \delta_{ij}) \cdot E_{i,j}$$

- Reasonable description of metals. Natural coupling to external fields
- Caveat: need untruncated Coulomb interactions

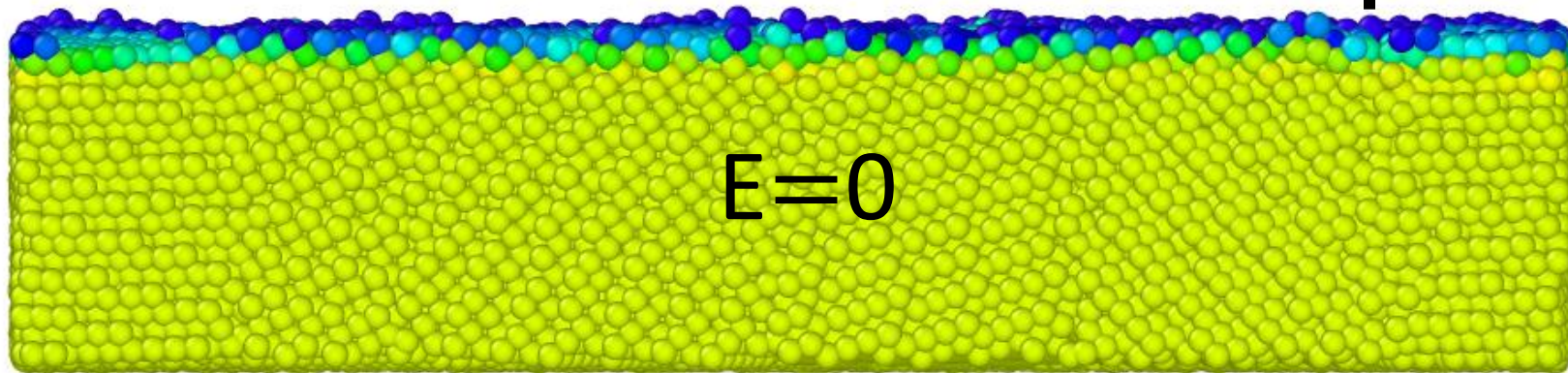
Q_{fixed}



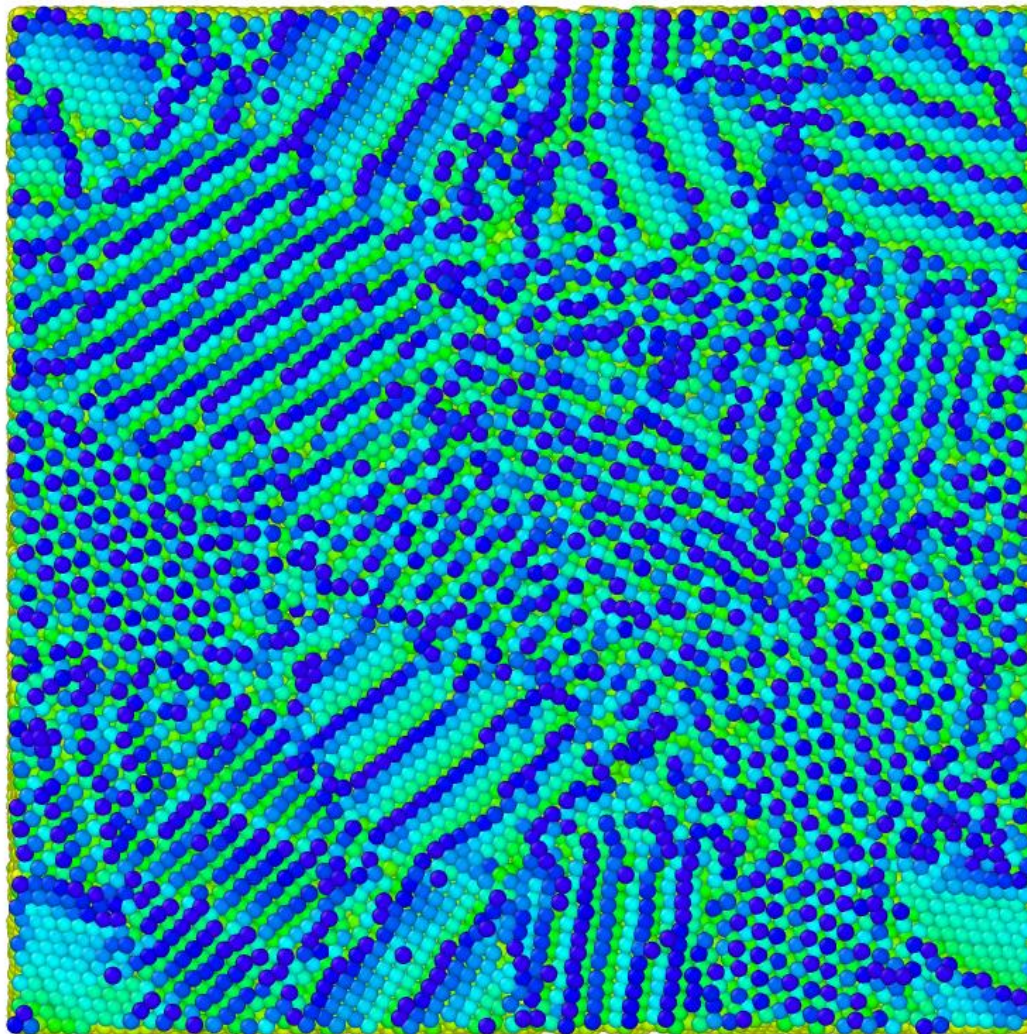
Q_{induced}

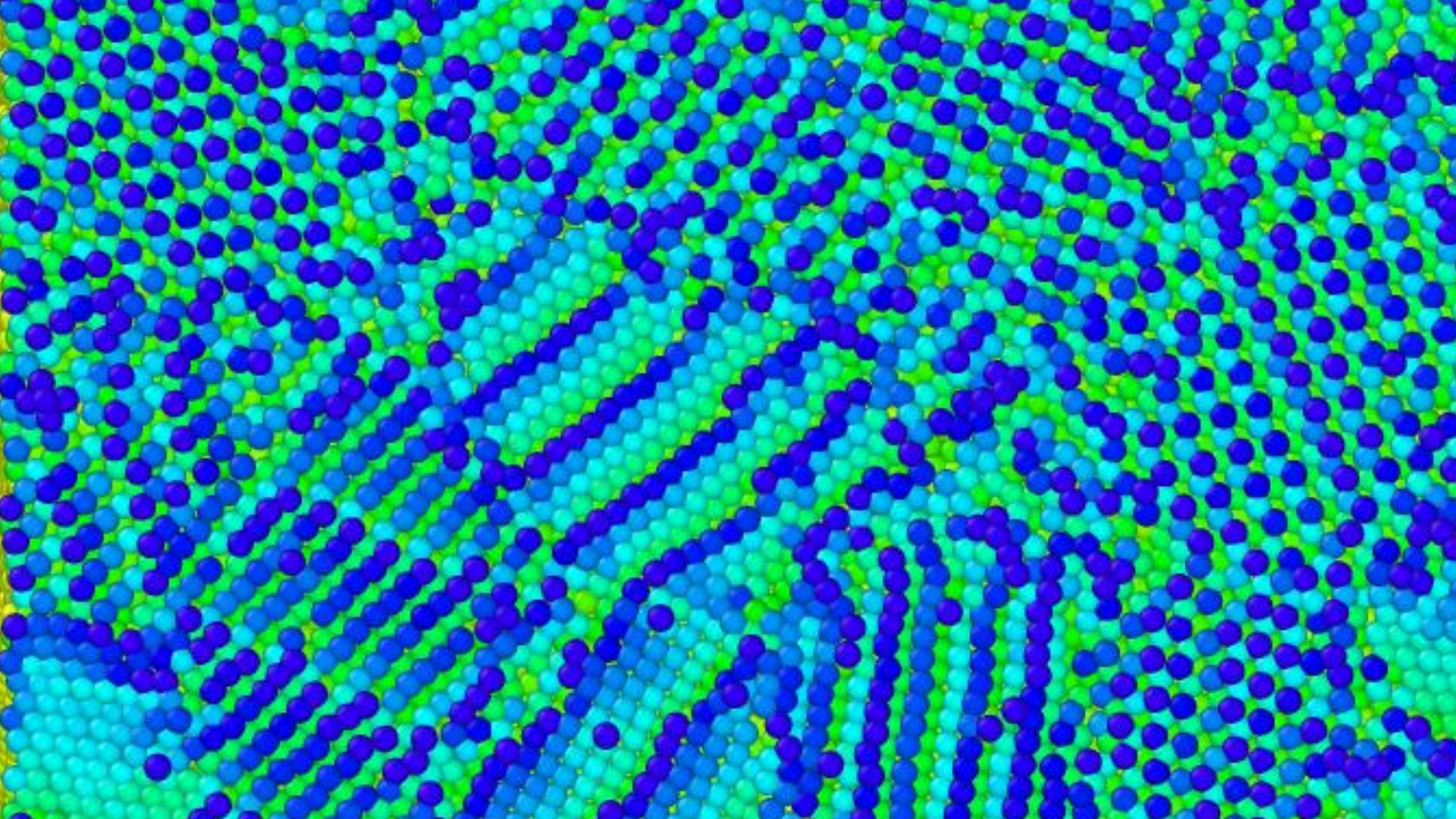
$E \neq 0$

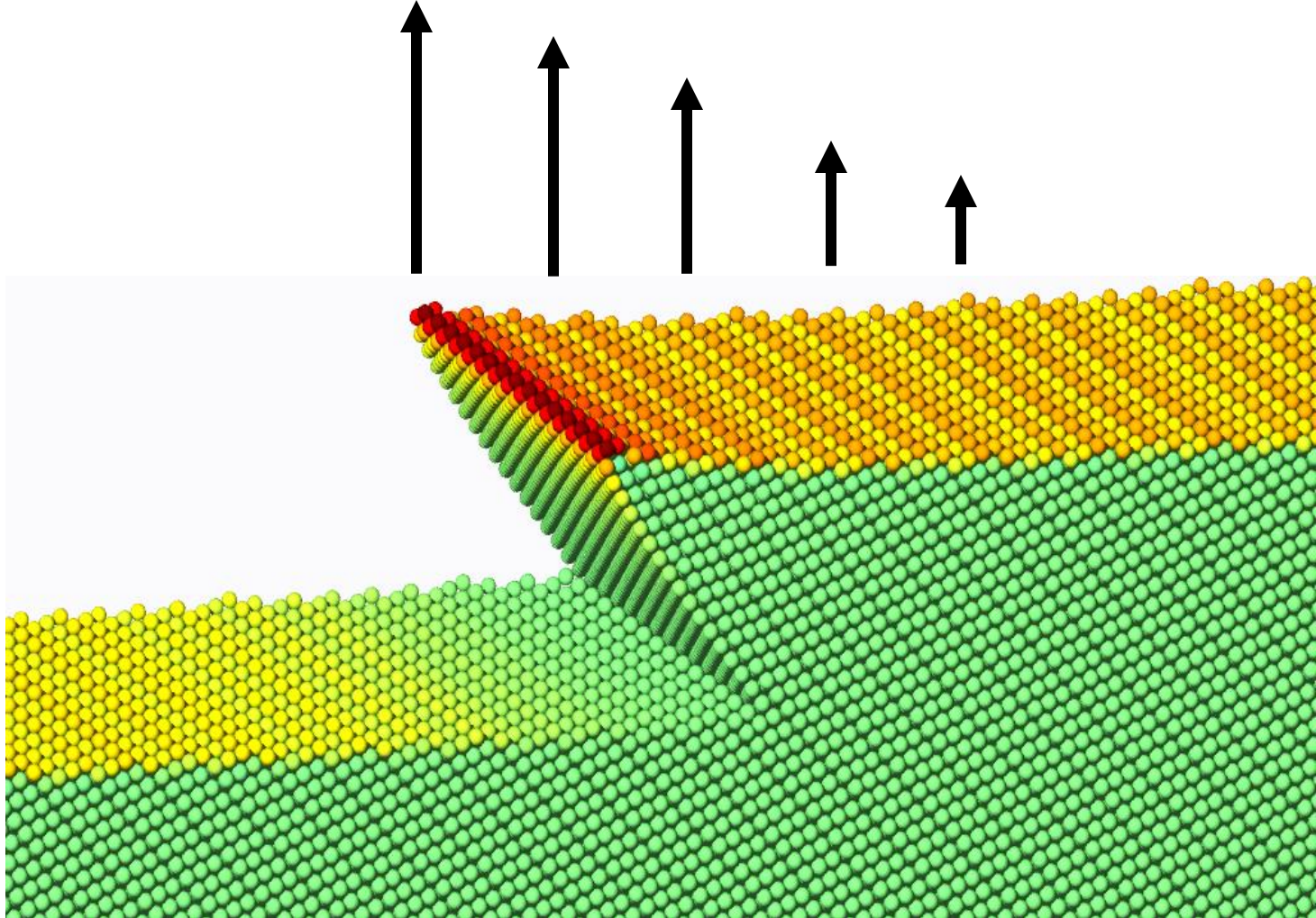
$\uparrow F_{\text{Maxwell}}$



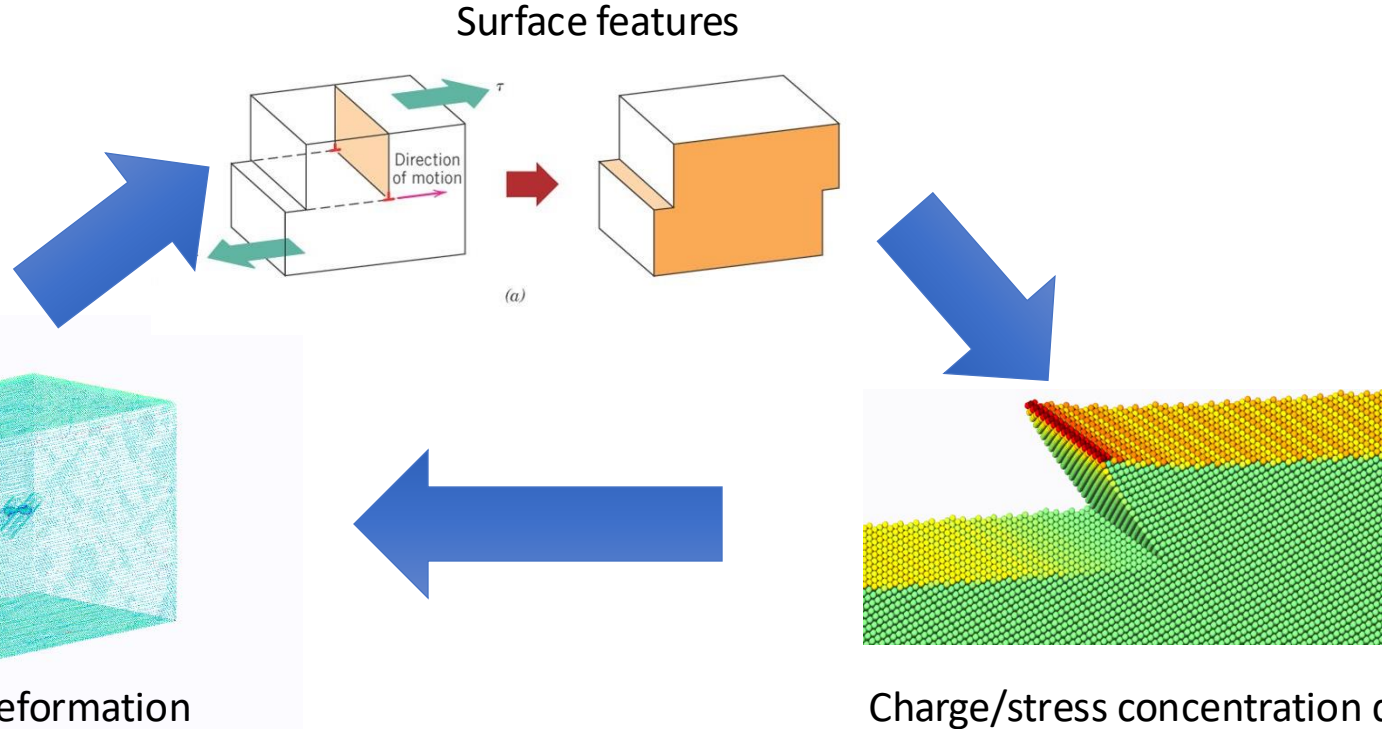
$E = 0$

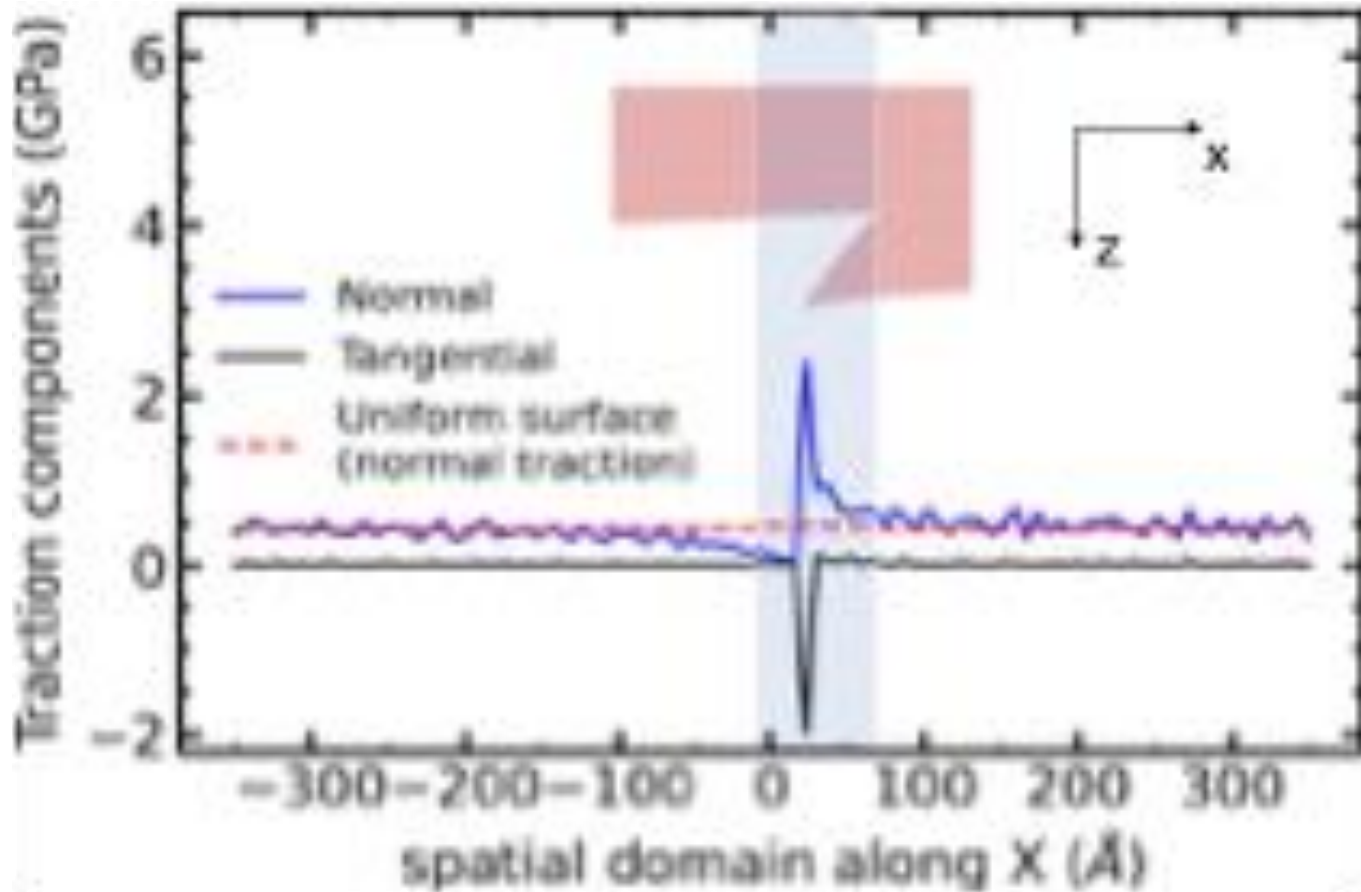






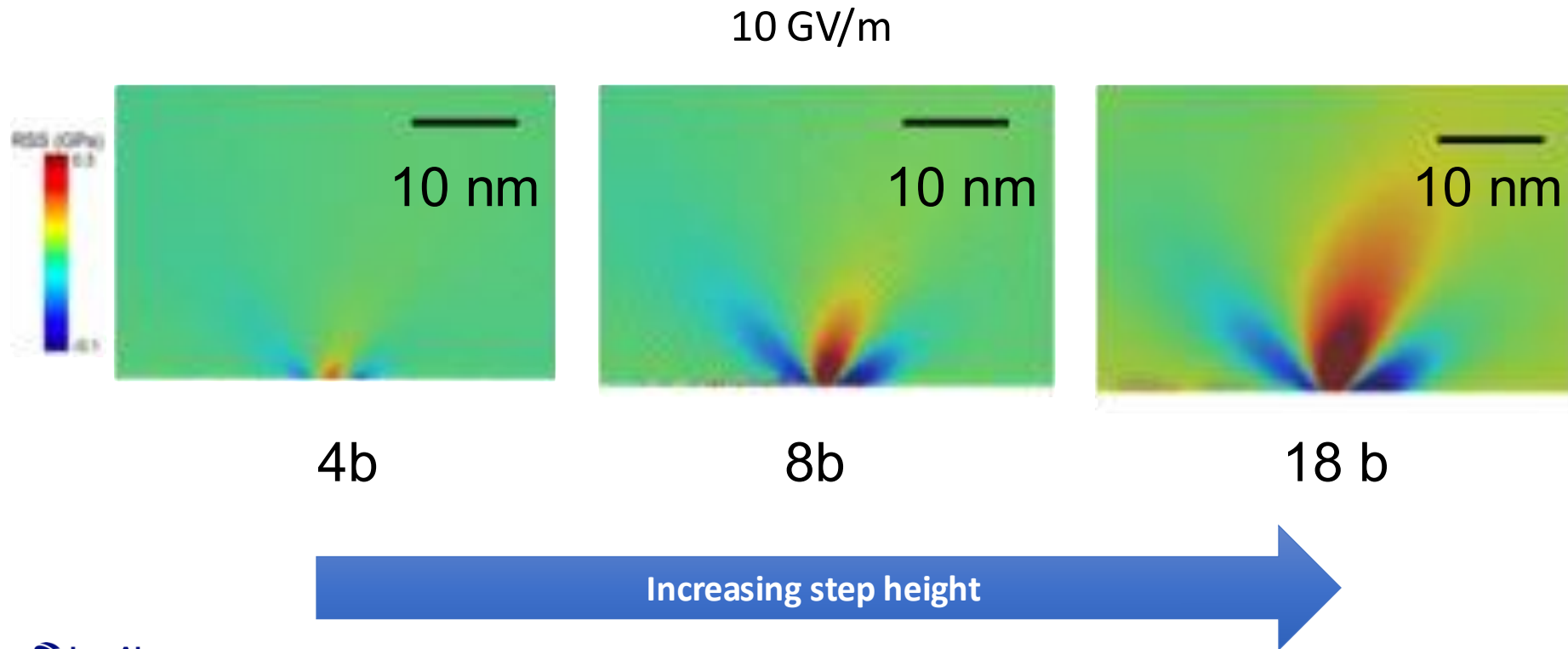
Runaway dislocation emission!






10 GV/m, step height = 18 b

Field/step coupling induces resolved shear stresses



Runaway dislocation emission?

Electric field	Maxwell stress on a flat surface	Critical Frank-Read source length	
10 MV/m	400 Pa	50 mm	
100 MV/m	40 KPa	0.5 mm	
1 GV/m	4 MPa	5 μm	
10 GV/m	400 MPa	50 nm	

- Yield strength of annealed Cu: ~ 30 MPa
- Peierls stress of Cu: ~ 0.3 MPa

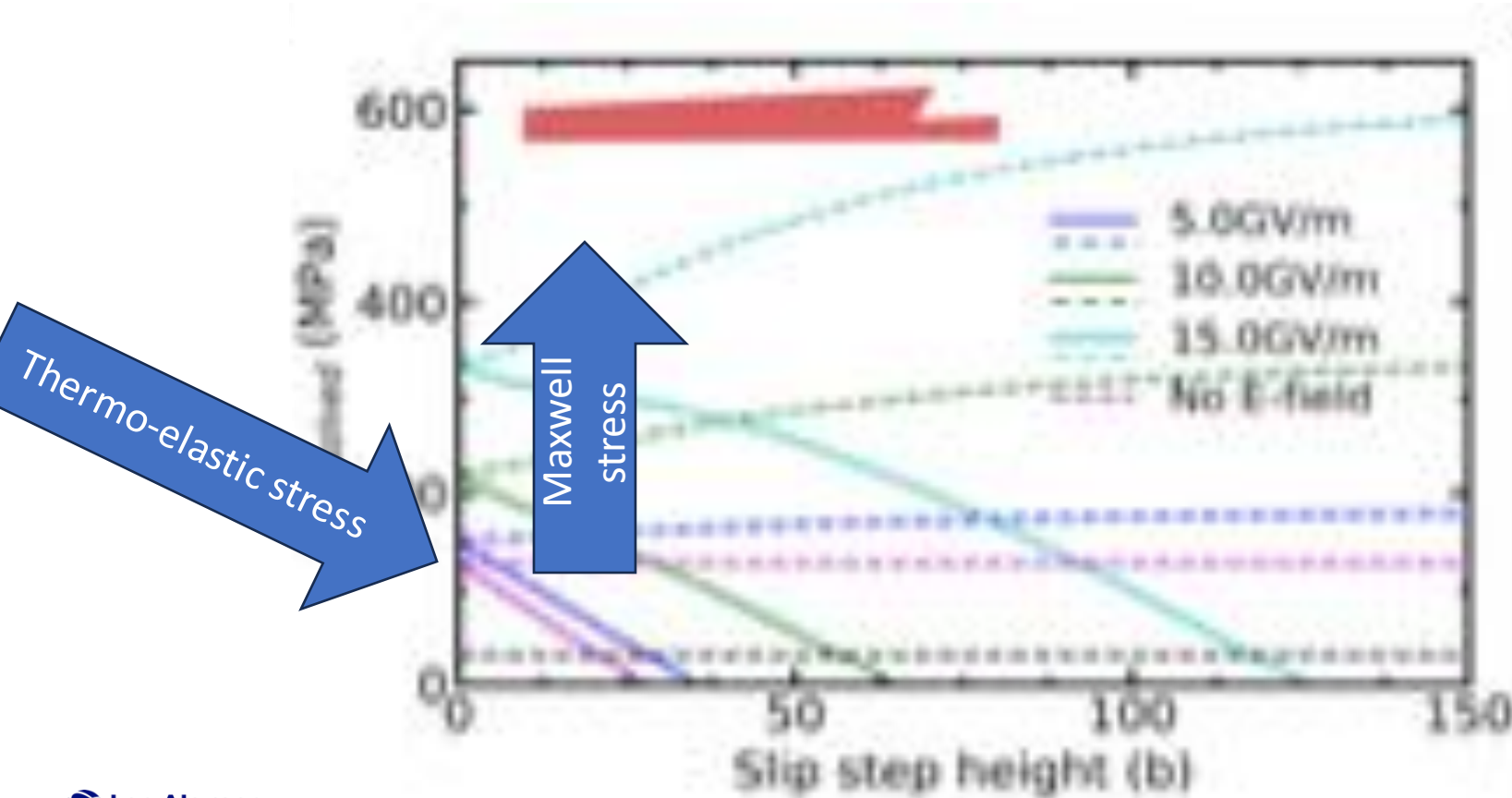
Runaway dislocation emission?

ΔT rise	Thermo-elastic stress
10 K	16 MPa
20 K	32 MPa
40 K	64 MPa
80 K	128 MPa

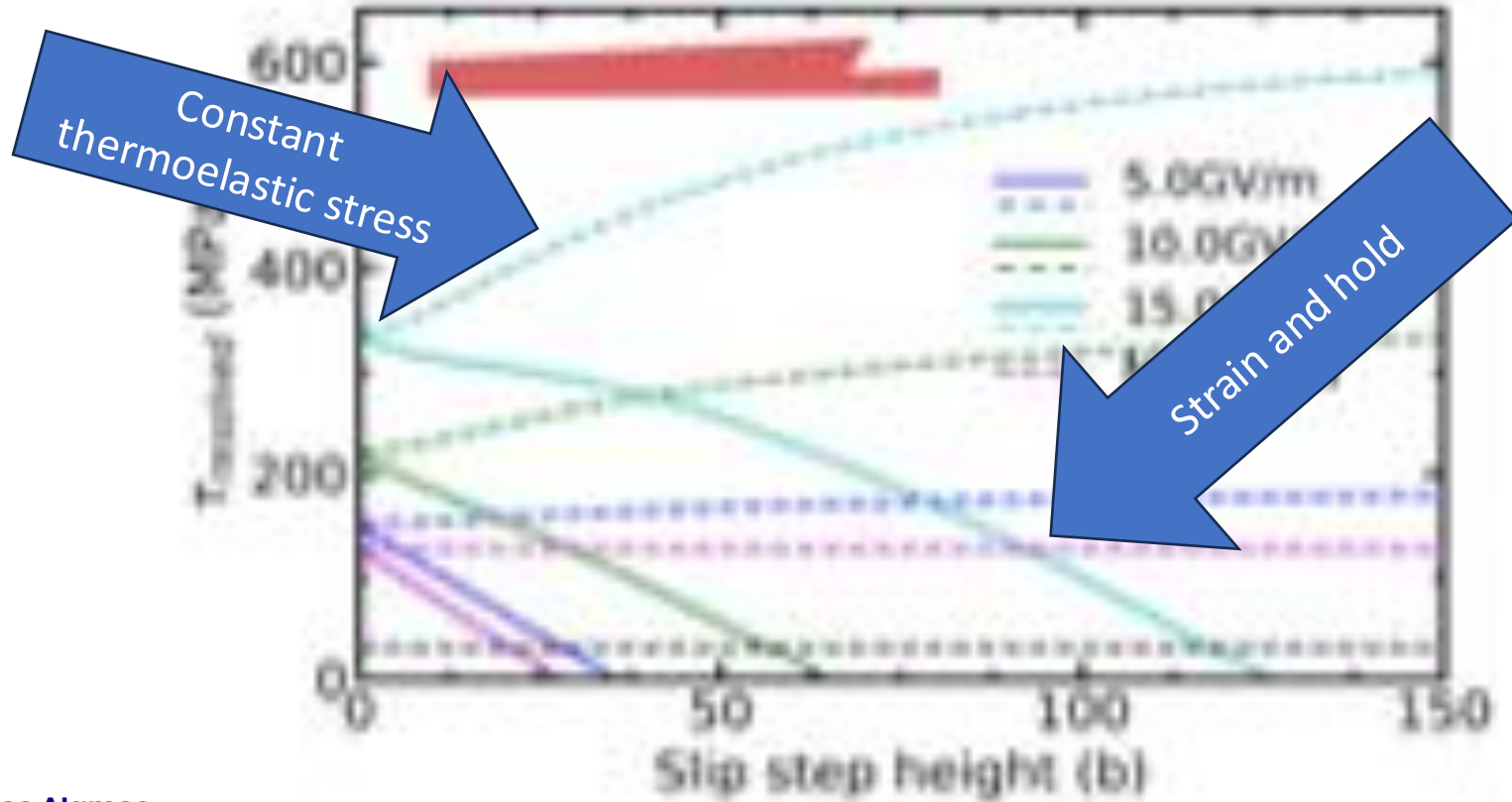


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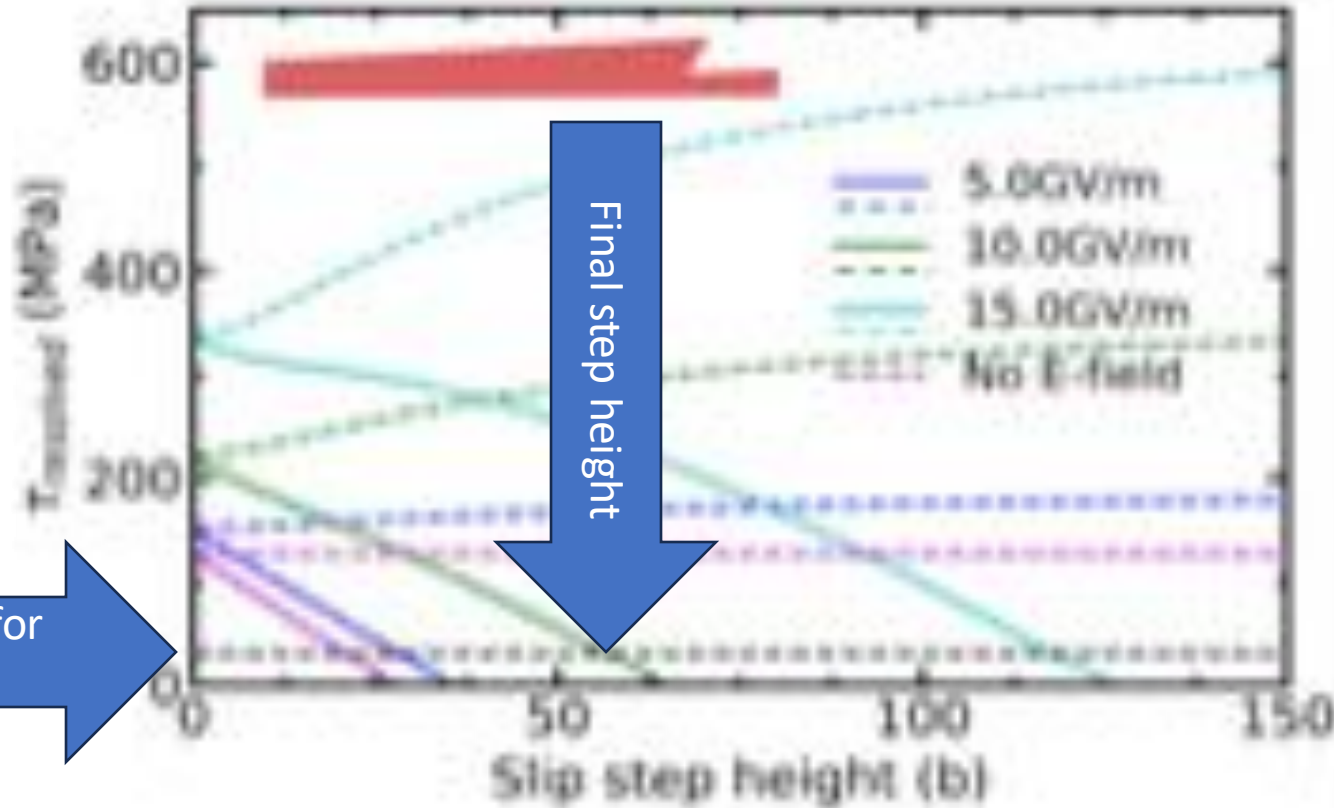
Dislocation emission at $\Delta T=80\text{K}$



Dislocation emission at $\Delta T=80\text{K}$

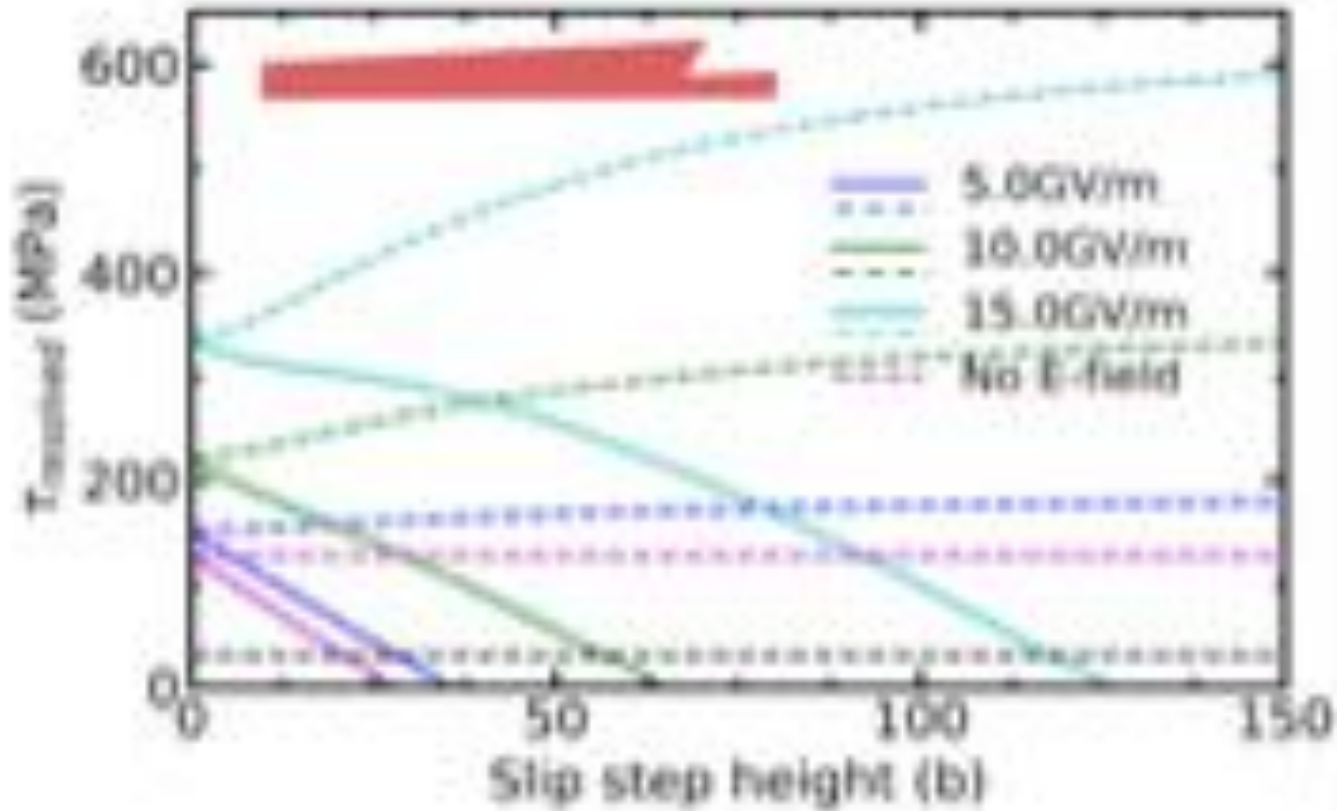


Dislocation emission at $\Delta T=80\text{K}$

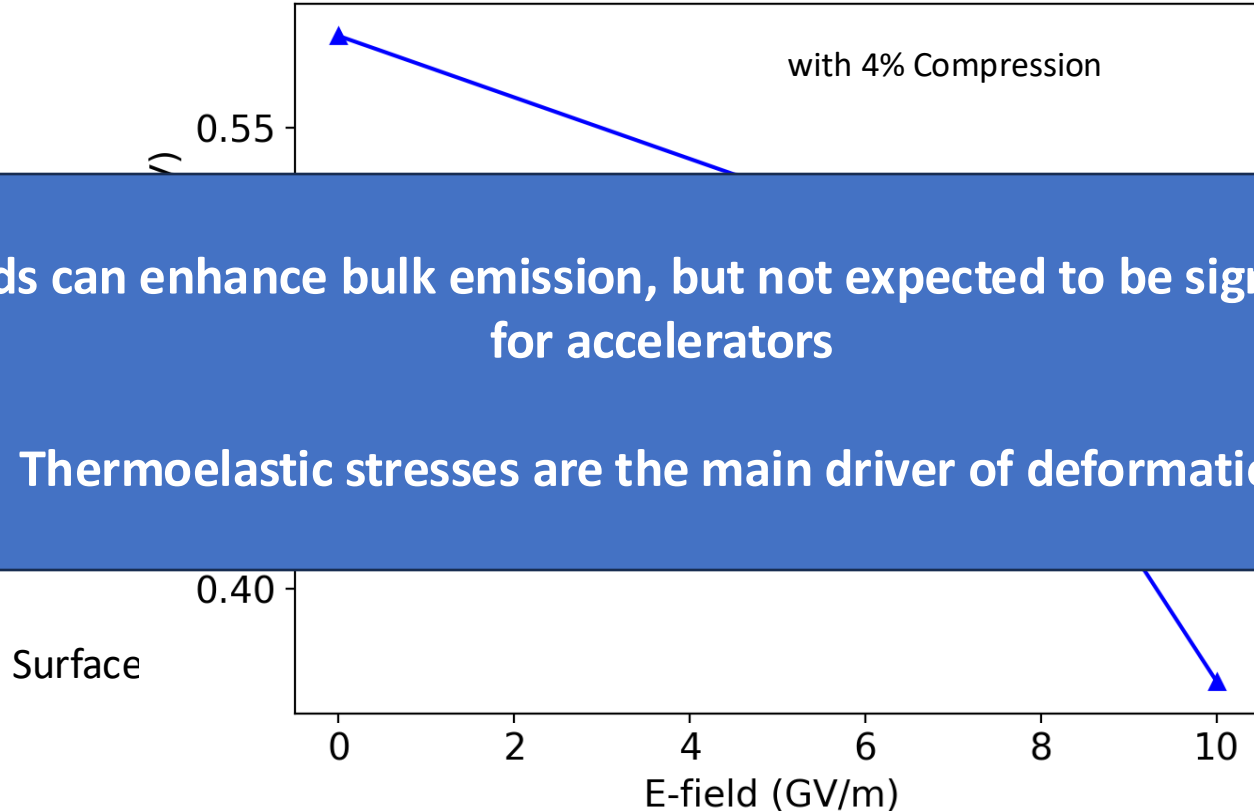


Critical stress for
OFHC Cu

Dislocation emission at $\Delta T=80\text{K}$

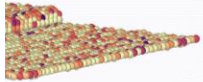


Surface dislocation multiplication



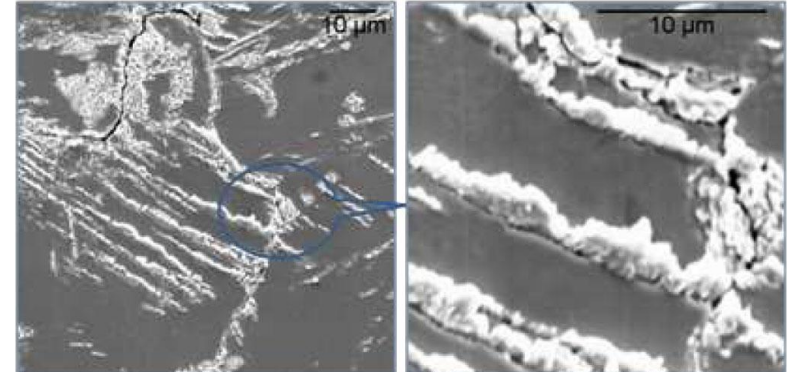
Fields can enhance bulk emission, but not expected to be significant for accelerators

Thermoelastic stresses are the main driver of deformation

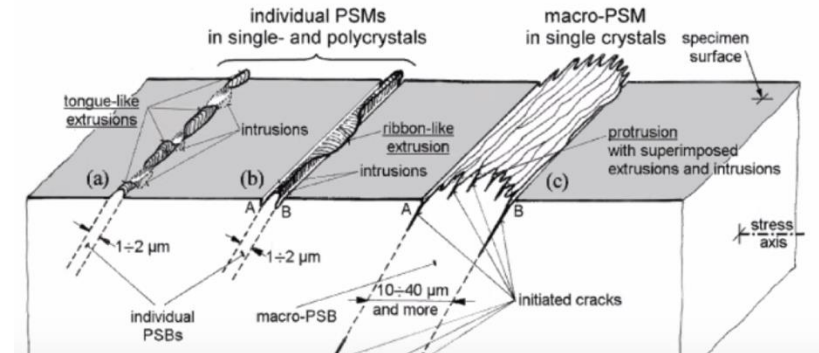


Vignette #1: Plastic-deformation induced roughening

- LARGE electric fields can enhance dislocation emission
- **Unlikely to be relevant for breakdown precursor formation**
- **Could activate once a precursor is formed by some other means**
- Thermal cyclic fatigue is a prime candidate.



[Laurent, Tantawi, Dolgashev et al. (2011)]



[Man et al. (2009)]

Vignette #1.1: Can we design better materials?

- **Design principle #1: minimize RF losses**
- **Design principle #2: maximize resolved shear stress for dislocation motion**
- **Design principle #3: dilute copper alloys are a good place to start**
- **Approach: high-throughput DFT calculations for dilute copper alloys**

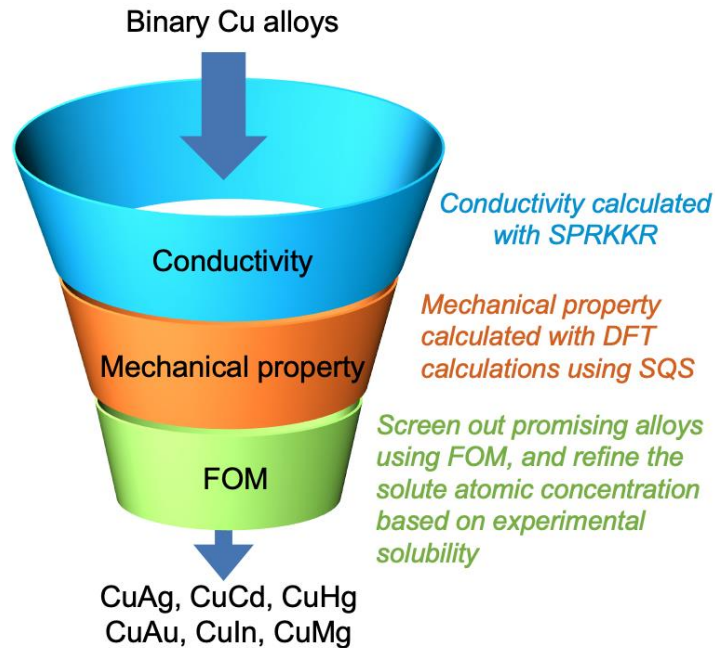
$$\text{FOM} = \frac{\tau_{L-N}}{\varepsilon_{thermal}}$$

Wang, Simakov, Perez. *Applied Physics Letters* 120, no. 13 (2022): 134101.

Wang, Simakov, Perez. *Journal of Applied Physics* 132, no. 17 (2022).

Vignette #1.5: Can we design better materials?

- **Design principle #1: minimize RF losses**
- **Design principle #2: impede dislocation motion**
- **Design principle #3: dilute copper alloys are a good place to start**
- Approach: high-throughput DFT calculations for dilute copper alloys



Wang, Simakov, Perez. *Applied Physics Letters* 120, no. 13 (2022): 134101.

Wang, Simakov, Perez. *Journal of Applied Physics* 132, no. 17 (2022).

FOM #1: Critical stress to move dislocations

Labusch–Nabarro (LN) model: Critical resolved shear stress required for dislocation motion:

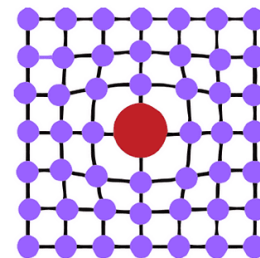
$$\tau_{L-N} = \frac{(2\omega f_m^4 c^2)^{1/3}}{2b^{7/3}(Gb^2)^{1/3}}$$

With:

$$f_m = \frac{Gb^2}{120} \varepsilon_L \quad \varepsilon_L = \sqrt{\varepsilon_G'^2 + (\alpha \varepsilon_b)^2} \left\{ \begin{array}{l} \alpha = 9 - 16 \\ \varepsilon_G' = \frac{\varepsilon_G}{1 + 0.5|\varepsilon_G|} \end{array} \right\}$$

Two key parameters:

- Size misfit $\varepsilon_b = \frac{db}{bdc}$
- Modulus misfit $\varepsilon_G = \frac{dG}{Gdc}$



Zander et al., Computational Materials Science 41 (2007) 86–95
Butt, Journal of Materials Science 28 (1993) 2557-2576

FOM #2: Thermal stress created by RF dissipation

- Assuming that the surface is free to relax in z only, the corresponding in-plane thermal stress is

$$\varepsilon_{xx} \equiv \varepsilon_{yy} \equiv -\frac{E\alpha\Delta T}{1-\nu}$$

- Heating due to RF losses can be estimated from the solution of the heat equation:

Accelerator parameters $\Delta T = \frac{G^2 \sqrt{T_p}}{Z_H^2} \frac{R_s}{\sqrt{\pi \rho c_\epsilon k}}$ Material properties

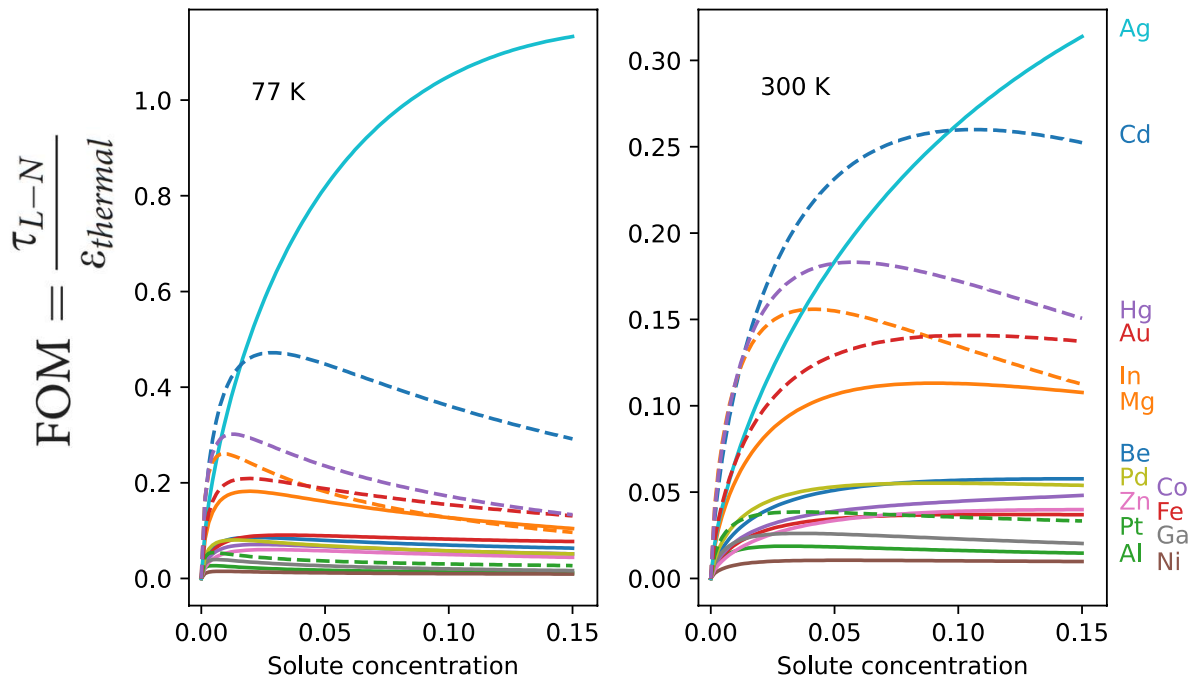
TABLE I. Parameters of a sample C-band accelerating structure.

Parameters	λ	T_p	G	Z_H
Values	0.052 m	1.0 μ s	100 MV/m	$\frac{Z_0}{1.25} = \frac{377 \Omega}{1.25} = 301.6 \Omega$

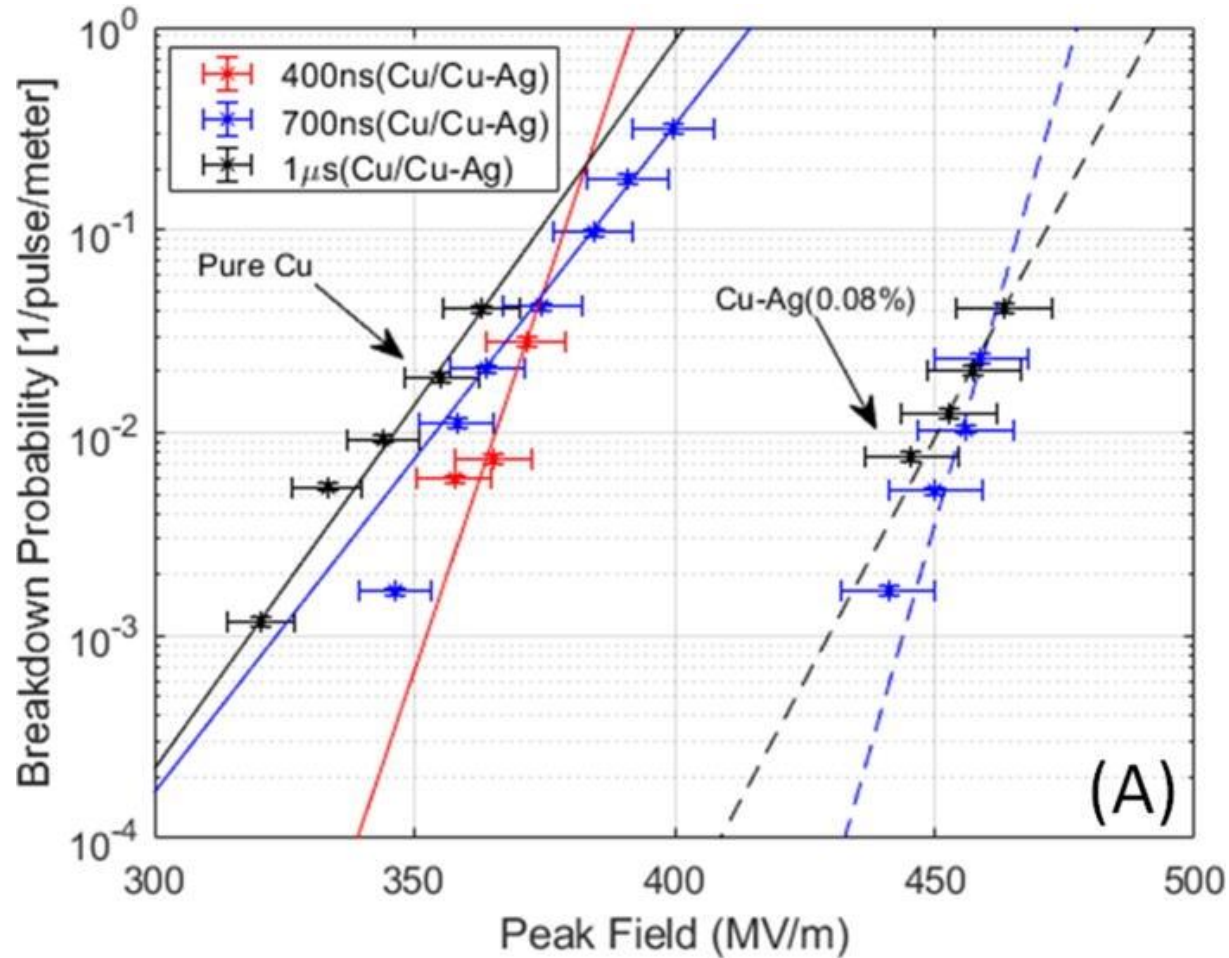
Perry B. Wilson. In ITP Conference on Future High Energy Colliders.
University of California, Santa Barbara, October 1996.

Alloy design

Ag, Cd, Hg, Au, In, and Mg stand out as potential alloying candidates.

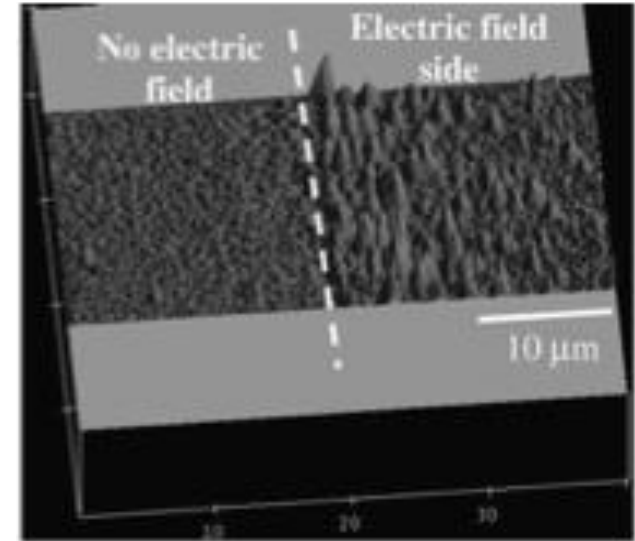


- **Ag, Cd:** excellent conductivity
- **Hg, In, Cd:** strong strengthening
- **Au, Mg:** decent at both



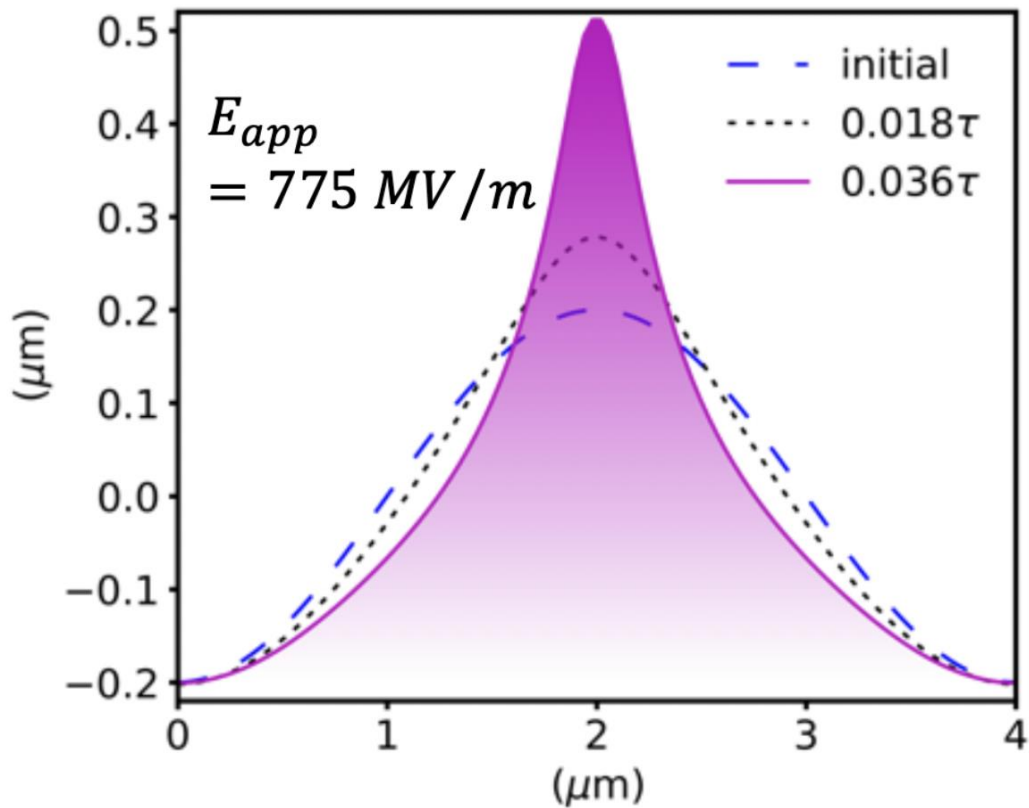
Vignette #2: Surface-transport induced roughening

- Surface roughening also occurs without thermo-elastic stress, e.g., under DC electric fields
- Suggests that another mass transport mechanism operates
- Prime suspect: **surface diffusion**

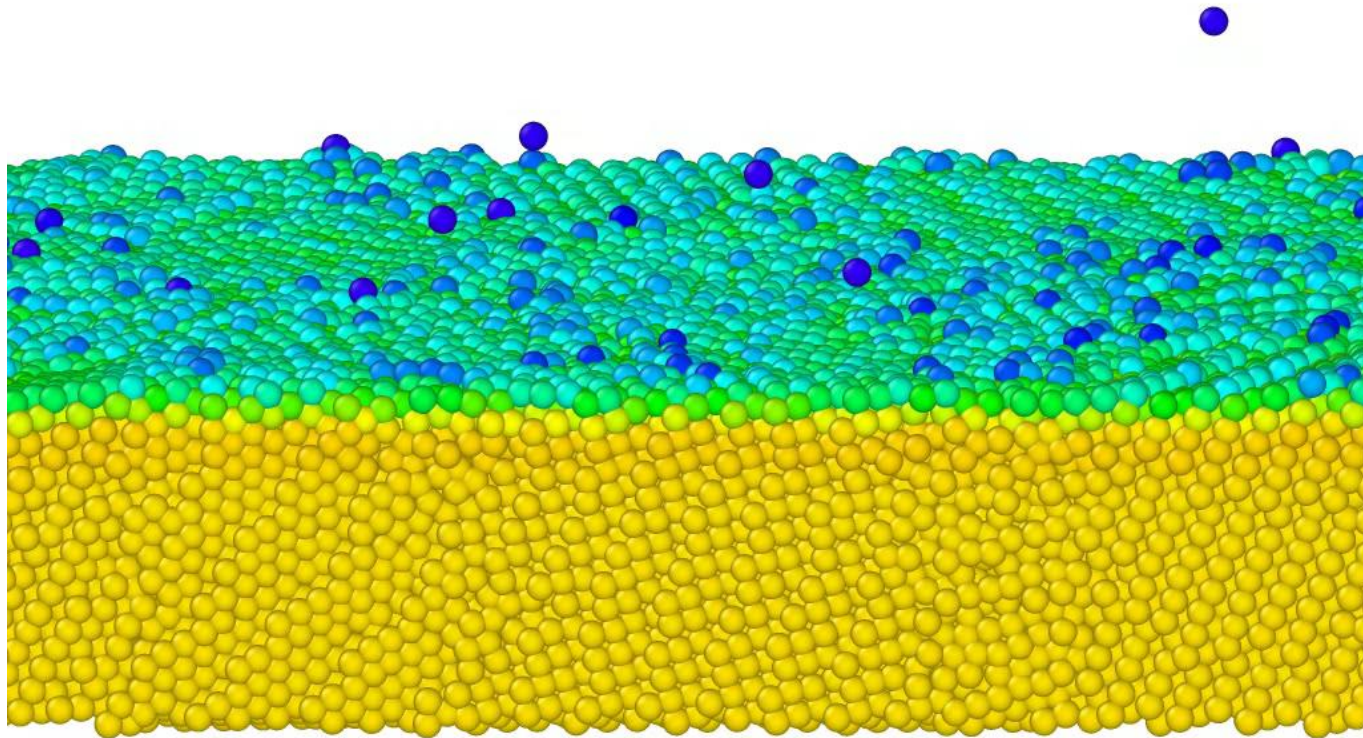


[Gill, Goduru, Sheldon (2008)]

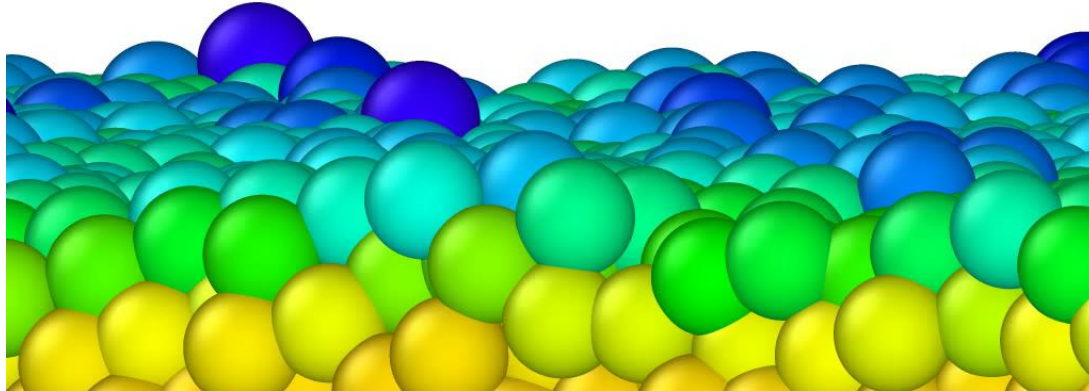
Physical intuition: field



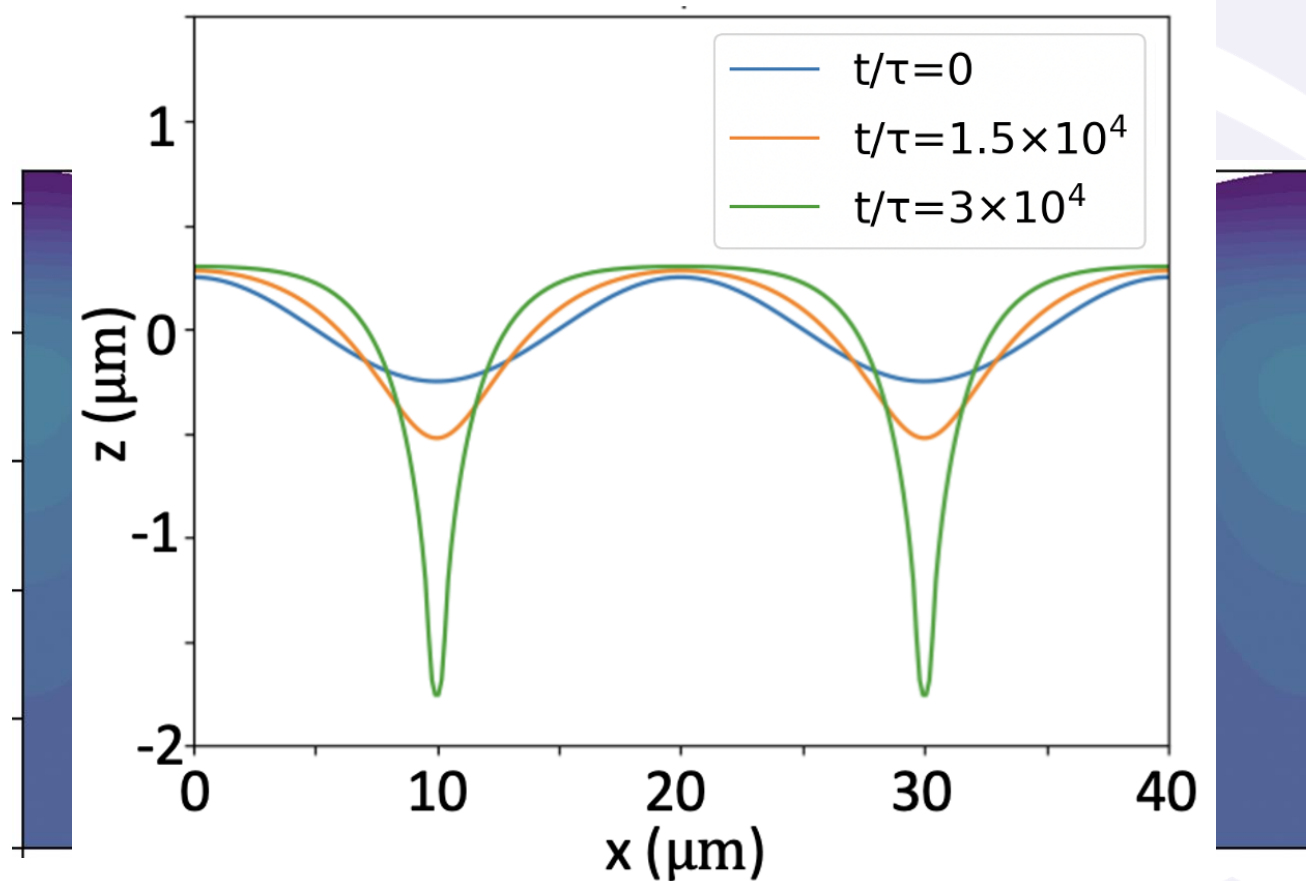
Direct atomistic simulations



Direct atomistic simulations



Physical intuition: thermo-elasticity



Linear stability analysis

Driving forces:

- Surface tension
- Electrostatic energy
- Thermo-elastic stresses

Dynamics:

- Surface diffusion along chemical potential gradient

Under an applied field \mathbf{E} and a stress caused by a temperature rise ΔT , the amplitude of a mode of wavenumber \mathbf{k} grows as:

$$h(t, k) = h_0(k) \exp(C(2k^3 \alpha^2 \Delta T^2 + k^3 \epsilon_0 E^2 - \gamma k^4)t)$$

Thermoelastic
stresses ↑

E-field ↑

Surface
tension ↓

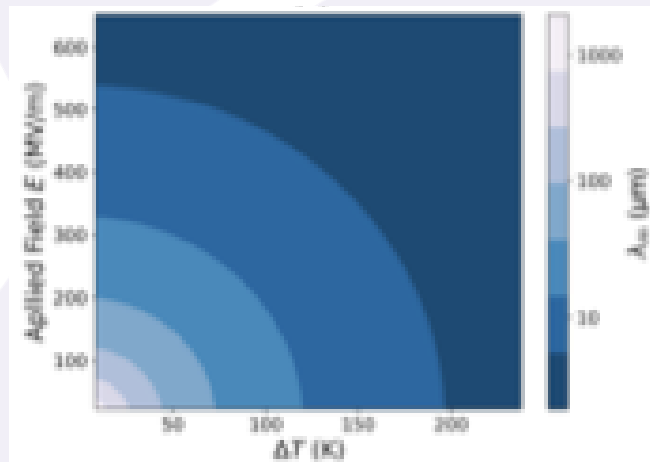
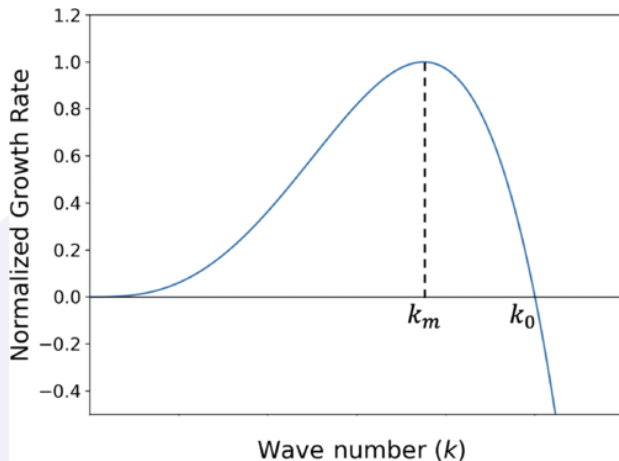
[Shinohara, Bagchi, Simakov, Baryshev, Perez (2024);
Song, Yang (2006); Du, Srolovitz (2004)]

Linear stability analysis

- Growth rate of the maximally-unstable mode is very sensitive to E and ΔT

$$h(t, k) \sim \exp\left(-\frac{E_b}{k_B(T + \Delta T)}\right) [E^2 + \Delta T^2]^4$$

- Very sharp dependence on E and ΔT**
- Non-linearities and finite amplitudes further increase coupling

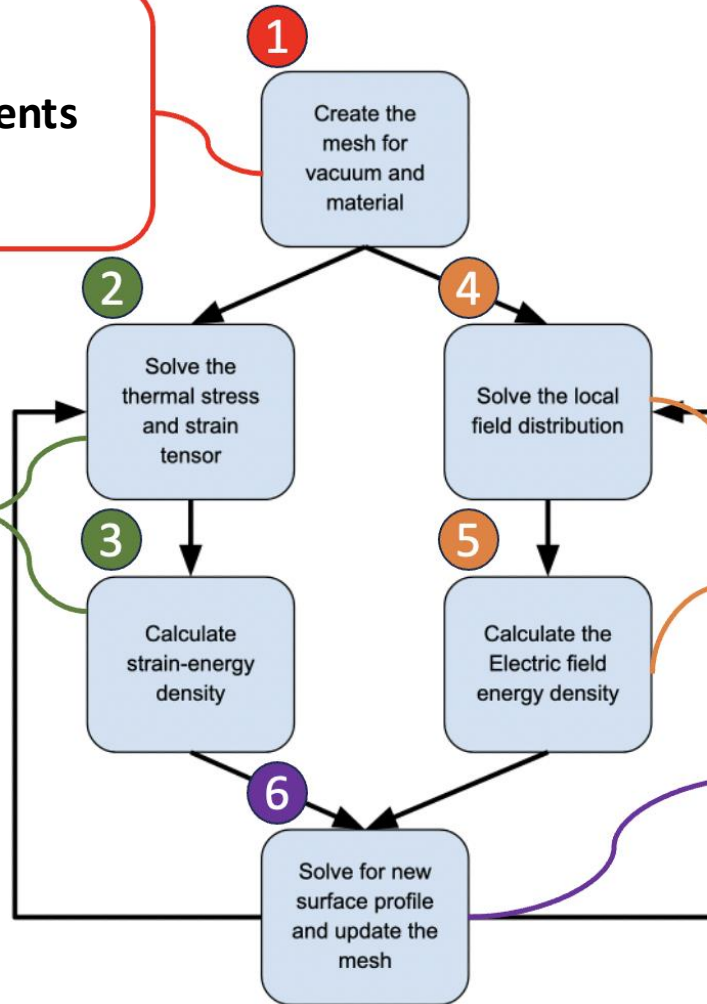


Method: 2D finite elements

**Driving force #2:
Thermo-elasticity
induced by resistive
heating**

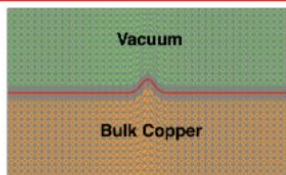
**Driving force #1:
Electrostatics of field-
induced charges**

**Surface diffusion along
chemical potential
gradient**



1

Finite Element Method



1. Local field distribution is solved on the vacuum mesh
2. Linear Thermoelasticity is solved on the copper mesh

2 & 3

Linear Thermoelasticity

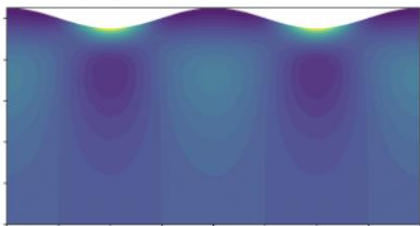
$$-\nabla \cdot \sigma(u) = 0$$

$$\sigma(u) = \lambda \text{tr}(\epsilon(u)) \mathbb{1} + 2\mu \epsilon(u) - \frac{\alpha Y}{1-2\nu} \Delta T \mathbb{1}$$

$$\epsilon(u) = \frac{1}{2} (\nabla u + (\nabla u)^T)$$

Strain-Energy Density

$$\omega_T = \frac{1}{2} \sum_i \sum_j \sigma_{ij} \epsilon_{ij} = \frac{1}{2} \left(\sigma_{11} \epsilon_{11} + \sigma_{22} \epsilon_{22} + \sigma_{12} \epsilon_{12} + \sigma_{21} \epsilon_{21} \right)$$



1

Create the mesh for vacuum and material

2

Solve the thermal stress and strain tensor

3

Calculate strain-energy density

4

Solve the local field distribution

5

Calculate the Electric field energy density

6

Solve for new surface profile and update the mesh

4 & 5

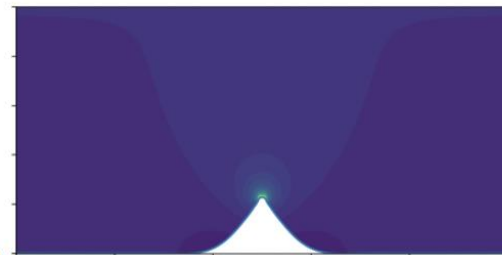
Electrostatic

$$\nabla \cdot (\nabla \phi) = 0$$

$$E = -\nabla \phi$$

Field Energy Density

$$U_E = \frac{1}{2} \epsilon_0 E^2$$



6

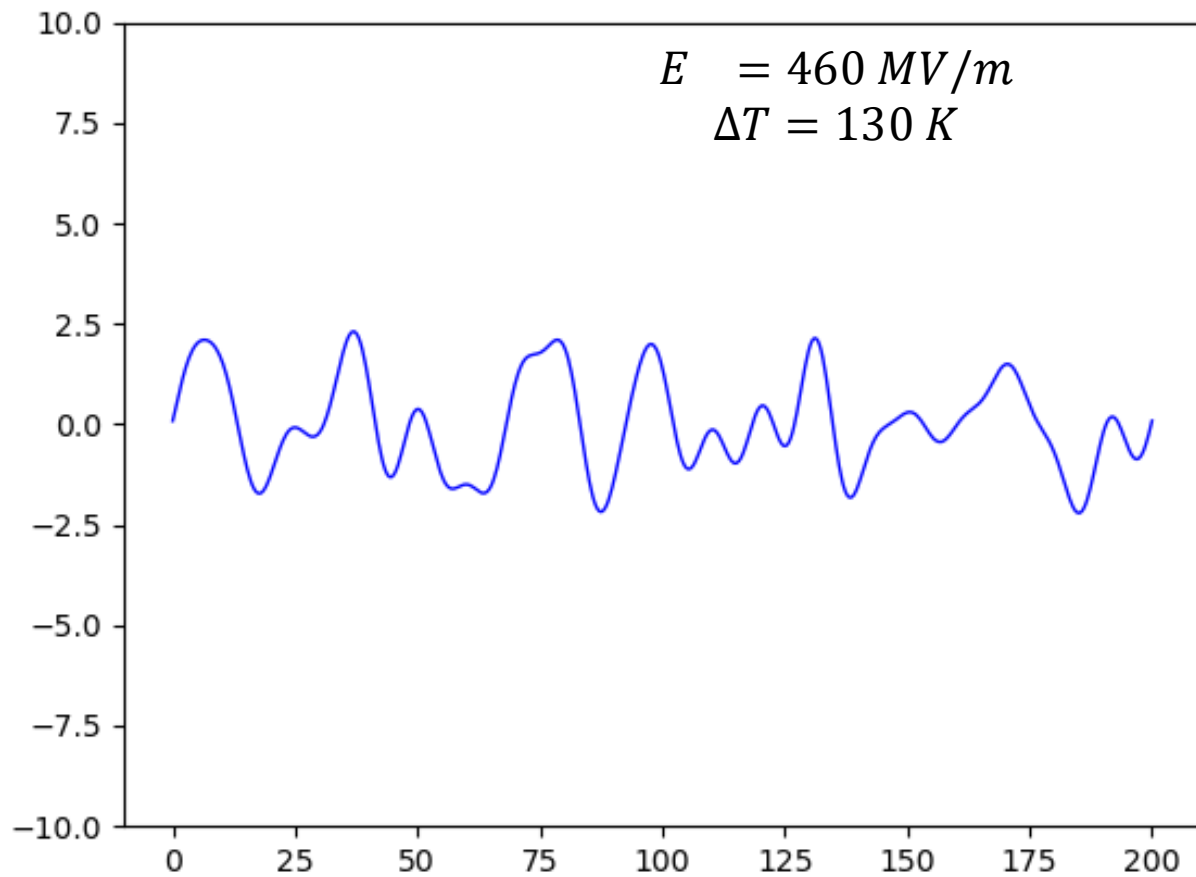
Surface Diffusion

$$V_n = \frac{D_s \Omega v_s}{k_b T} \frac{\partial^2 \mu_c}{\partial s^2}$$

$$\frac{\partial h}{\partial t} = \frac{D_s v_s \Omega}{k_B T} \frac{\partial}{\partial x} \left[(1 + h_x')^{-1/2} \frac{\partial}{\partial x} (\mu_c) \right]$$

$$\mu_c = \Omega (\gamma k - U_E + \omega_T)$$

Chemical potential = surface tension + electrostatic energy + strain energy density



Tip runaway phase diagram

- **Nominal surface features:**

- Th
- lo
- To
- at

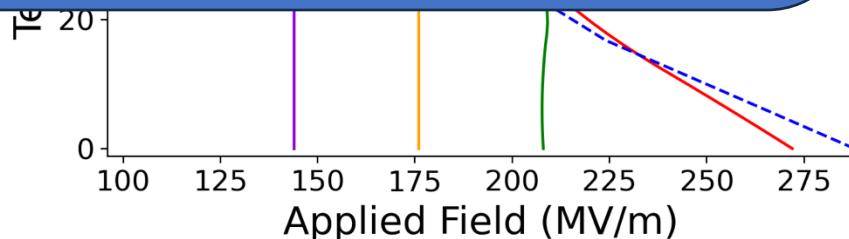
- **Sha**

- E
- R

- **Con**

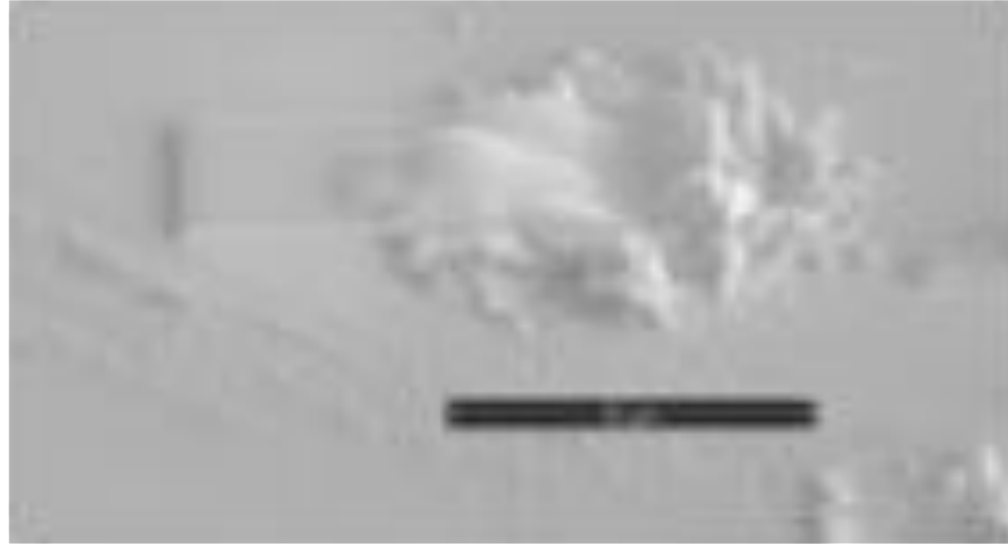
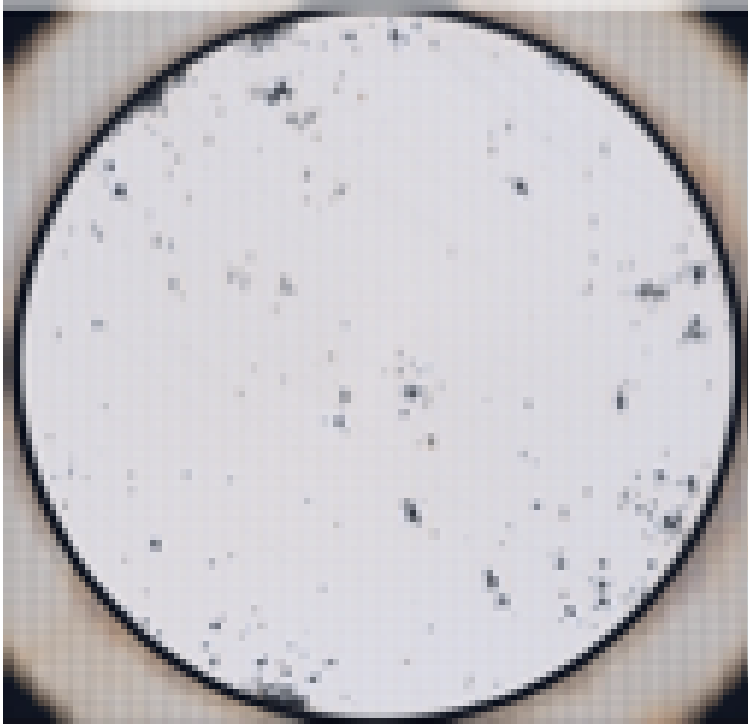
- precursor formation around $E_{\text{th}} \approx 200$ MV/m
- increased breakdown with cyclic heating
- secondary breakdowns

Roughening through surface diffusion can naturally explain the formation of breakdown precursors in accelerator-relevant conditions!



Runaway

Most breakdown events are “secondary”

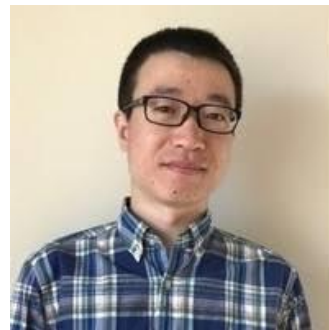


Summary

- Breakdown likely originates from multiple synergistic and competing factors
- In “standard” room temperature RF operation, it is plausible that:
 - Thermoelastic effects such create initial roughness
 - Field-driven surface diffusion sharpens precursors
 - For near-critical precursors, field-enhanced plasticity also activates
 - Previous breakdown sites act as likely nucleation sites for further breakdown
- The kinetic competition between the different modes needs to be better understood
- Other factors are likely to be important: oxide layers, contaminant molecules, impurities,... More work required.

Acknowledgements

- **Soumendu Bagchi:** MD simulations, FEM modeling
- **Ryo Shinohara:** FEM modeling, generalization to semi-conductors
- **Gaoxue Wang:** Materials Design



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